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	Application No.	Applicant(s)
Notice of Allowability	09/960,694	KOTOKU, KENICHI
	Examiner	Art Unit
	Parviz Hassanzadeh	1763
The MAILING DATE of this communication ap All claims being allowable, PROSECUTION ON THE MERITS herewith (or previously mailed), a Notice of Allowance (PTOL-6 NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT of the Office or upon petition by the applicant. See 37 CFR 1.3	ÍS (OR REMAINS) CLOSED in the 35) or other appropriate communion RIGHTS. This application is sub	is application. If not included cation will be mailed in due course. THIS
 1.	•	· (f).
 Certified copies of the priority documents had 	ave been received.	
Certified copies of the priority documents had	ave been received in Application I	No
Copies of the certified copies of the priority	documents have been received in	n this national stage application from the
International Bureau (PCT Rule 17.2(a)).		
* Certified copies not received: 5. Acknowledgment is made of a claim for domestic priority reference was included in the first sentence of the speci		
(a) The translation of the foreign language provisional	• •	
6. Acknowledgment is made of a claim for domestic priority in the first sentence of the specification or in an Applicat	ion Data Sheet, 37 CFR 1.78.	
Applicant has THREE MONTHS FROM THE "MAILING DATE" below. Failure to timely comply will result in ABANDONMENT	' of this communication to file a re of this application. THIS THREE	ply complying with the requirements noted E-MONTH PERIOD IS NOT EXTENDABLE
7. A SUBSTITUTE OATH OR DECLARATION must be sul INFORMAL PATENT APPLICATION (PTO-152) which s	bmitted. Note the attached EXAM gives reason(s) why the oath or d	INER'S AMENDMENT or NOTICE OF eclaration is deficient.
 CORRECTED DRAWINGS (as "replacement sheets") n (a) including changes required by the Notice of Draftsp 1) hereto or 2) to Paper No 		PTO-948) attached
(b) ☐ including changes required by the proposed drawin	g correction filed, which h	nas been approved by the Examiner.
(c) ☐ including changes required by the attached Examin	er's Amendment / Comment or in	the Office action of Paper No
Identifying indicia such as the application number (see 37 CFF each sheet. Replacement sheet(s) should be labeled as such i		
9. DEPOSIT OF and/or INFORMATION about the de attached Examiner's comment regarding REQUIREMENT FOR		
Attachment(s)		
1 Notice of References Cited (PTO-892)	5☐ Notice of Inform	nal Patent Application (PTO-152)
2 Notice of Draftperson's Patent Drawing Review (PTO-948		nary (PTO-413), Paper No
3 Information Disclosure Statements (PTO-1449 or PTO/SB Paper No.	^(/08) , 7⊠ Examiner's Am	endment/Comment
Examiner's Comment Regarding Requirement for Deposit of Biological Material	8⊠ Examiner's Sta 9∏ Other .	tement of Reasons for Allowance
		Parviz Hassanzadeh Primary Examiner Art Unit: 1763

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DETAILED ACTION

EXAMINER'S AMENDMENT

EX. Amdt.

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Daniel S. Glueck on 12/15/03.

The application has been amended as follows:

IN THE LAIMS:

Have canceled non-elected claims 13-17.

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It is also noticed that claim 17 is a method claim and is restricted as being directed to a method of sequentially performing projection exposure of device patterns in a pattern effective area of a photo-mask onto shot area of a wafer, wherein the method does not require a wafer stage moving a wafer in one of a mask scanning direction and a direction opposite to the mask scanning direction.

Allowable Subject Matter

Claims 1-12 are allowed.

The following is an examiner's statement of reasons for allowance: an exposure apparatus for sequentially performing projection exposure of device patterns in a pattern effective area of a photo-mask onto shot area of a wafer, the apparatus including:

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an illumination unit for collectively illuminating the entire pattern effective area of the photo-mask with exposure light, wherein the photo-mask is contained within the illumination range of the illumination unit.

Neither of the prior art of the record teaches or suggests an illumination unit collectively exposing an entire pattern effective area of a photo-mask.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Parviz Hassanzadeh whose telephone number is (571)272-1435.

The examiner can normally be reached on Tuesday-Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Gregory Mills can be reached on (703)308-1633. The fax phone number for the organization where this application or proceeding is assigned is (703) 872-9306.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703)308-0661.

Parviz Hassanzadeh Primary Examiner Art Unit 1763

December 15, 2003